

FORM PTO-1449 (Modified)			Attorney Docket No.: 020185-00011008		Application No.: 09911,763	
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)			Applicant: Farid Askari		Filing Date: July 23, 2001	
			Group: 2857		Page: 1	
Reference Designation			U.S. PATENT DOCUMENTS			
Examiner Initial	Document No.	Date	Name	Class	Sub-class	Filing Date (If Appropriate)
<i>h</i> 0001	4,818,873	04/1989	Herriot	250	310	
<i>h</i> 0002	5,644,512	07/1997	Chernoff et al.	364	571.02	
FOREIGN PATENT DOCUMENTS						
	Document No.	Date	Country	Class	Sub-class	Translation (Yes/No)
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)						
<i>h</i> 0003	Ronald Dixon et al, National Institute of Standards and Technology, "Dimensional Metrology with the NIST Calibrated Atomic Force Microscope", Proceedings of SPIE, Volume 3677, pp. 20-34, 1999					
0004	S.R. Dooley et al, "Comparison of discrete subsample time delay estimation methods applied to narrowband signals", Measurement Science and Technology, Volume 9, pp. 1400-1408, 1998					
0005	Scott C. Douglas, "A Frequency Domain Subpixel Position Estimation Algorithm for Overlay Measurement", Proceedings of SPIE, Volume 1926, pp. 402-405, 1993					
0006	D. M. Holburn et al, "A Pattern Recognition Technique Using Sequence of Marks for Registration in Electron Beam Lithography", Journal of Vacuum Science and Technology, Volume 19(4), pp. 1229-1233, 1981					
0007	Fumio Mizuno et al, "Evaluation of the long-term stability of critical-dimension measurement scanning electron microscopes using a calibration standard", Journal of Vacuum Science and Technology B, Volume 15(6), pp. 2177-2190, 1997					
0008	Anatoly Shchemelinin et al, "Basic Challenges of Optical Overlay Measurement", Proceedings of SPIE, Volume 3050, pp. 425-431, 1997					
0009	J.S. Villarubia et al, National Institute of Standards and Technology, "Intercomparison of SEM, AFM, and Electrical Linewidths", Proceedings of SPIE, Volume 3677, pp. 587-597, 1999					
0010	Alexander I. Zaslavsky, "Overlay Measurement and Edge Detection Methods", Proceedings of SPIE, Volume 3050, pp. 418-424, 1997					
<i>h</i> 0011	N. F. Zhang et al, National Institute of Standards and Technology, "A New Algorithm for the Measurement of Pitch in Metrology Instruments", Proceedings of SPIE, Volume 2725, pp. 147-158, 1996					
EXAMINER <i>Gr V Cus</i> DATE CONSIDERED <i>4-27-04</i>						

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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